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Arnaud Bouissonnié, Damien Daval, François Guyot, Philippe Ackerer. The dissolution anisotropy of pyroxenes: Experimental validation of a stochastic dissolution model based on enstatite weathering. Journal of Physical Chemistry C, 2020, 124 (5), pp.3122-3140. 10.1021/acs.jpcc.9b10824 . hal-03010516

HAL Id: hal-03010516 https://hal.science/hal-03010516

Submitted on 17 Nov 2020

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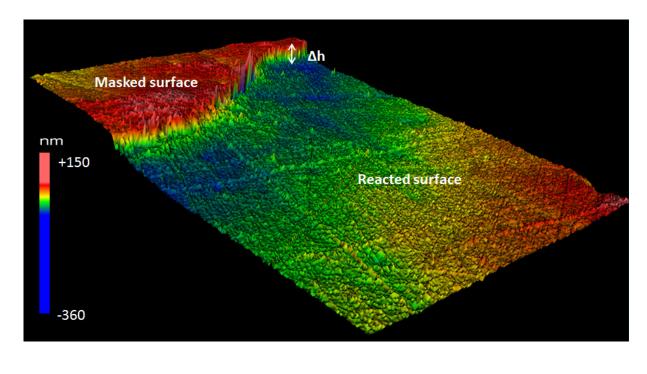
1	The dissolution anisotropy of pyroxenes: Experimental validation
2	of a stochastic dissolution model based on enstatite weathering
3	
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14	

15 Abstract

16 The understanding of the atomic-scale mechanisms controlling silicate dissolution represents a necessary prerequisite for the success of upscaling exercises aimed at predicting 17 18 the rates of water-silicate interactions over large space and time scales. In that respect, it has 19 been recently shown that physically-based stochastic models of crystal dissolution at the 20 atomic scale represent a promising alternative to the conventional treatment of silicate 21 dissolution rates, which consists in using empirical rate laws adjusted to the results of powder 22 dissolution experiments. However, most stochastic simulations conducted so far have been 23 based on simple cubic solid structure, and very few were directed to ascertaining the extent to 24 which the simulation outputs quantitatively compare to experimental measurements. In the 25 present study, we take advantage of the anisotropic crystallographic structure and reactivity of 26 chain silicates (pyroxenes) to tackle this issue. Face-specific enstatite dissolution experiments 27 conducted at pH 0 and 90 °C reveal that the face-specific dissolution rates observe the following trend: $r^{(001)} \gg r^{(210)} > r^{(010)} \ge r^{(100)}$. Electron microscopy characterizations 28 29 additionally show that lenticular etch pits elongated following the c axis grow on (hk0) faces, 30 and that nm-thick amorphous Mg-depleted layers cover the reacted enstatite surfaces. A 31 stochastic model was developed, and we show that simulations conducted with bond-breaking 32 probability ratios (and therefore, activation energy differences) that are consistent with the 33 existing literature regarding the hydrolysis of Mg-O-Mg, Mg-O-Si and Si-O-Si bonds can 34 quantitatively account for the measured dissolution rates. In addition, the lenticular shape, the 35 orientation and the symmetry of the pits generated numerically on (hk0) faces are also 36 consistent with those observed experimentally, while predicting the formation of Mg-depleted 37 surface layers. As a consequence, this study provides a first milestone to the application of 38 stochastic simulations to investigate the dissolution of pyroxenes.

39 *Keywords*: stochastic model; pyroxene dissolution anisotropy; dissolution kinetics.

40 Abstract graphic



43 **1. Introduction**

44 The interactions between aqueous fluids and silicates play a central role in many major 45 geological, environmental and industrial processes. Silicate dissolution and precipitation reactions control on various space and time scales many aspects of the continental surfaces 46 47 such as providing nutrients to living organisms¹, participating to the surface water chemistry, mobilizing² or sequestrating natural and anthropic contaminants³, shaping landscapes⁴ and 48 ultimately regulating the long-term carbon cycle and climate⁵⁻⁶. On an equal footing, 49 50 predicting the reactivity of silicate surfaces is further important for industrial purposes, such as cement hydration⁷⁻⁸ and kinetics of catalyzed reactions⁹. As a consequence, the dissolution 51 52 rates of silicates have now been investigated for more than half a century, giving rise to a dense body of literature (e.g. Brantley et al.¹⁰ for a review). 53

54 From a mechanistic standpoint, the conventional treatment of mineral reactivity has long 55 been based on the fundamental assumption that silicate dissolution may be described within the framework of the transition state theory (TST), early developed by Eyring¹¹ for 56 elementary and homogeneous reactions. The extension of TST by Aagaard and Helgeson¹² to 57 58 heterogeneous fluid-solid reactions supposes that silicate dissolution reactions are controlled 59 by a unique rate-limiting step, implicitly requiring that the surface reactivity is homogeneous, isotropic and immutable for a given fluid composition¹³. Although the resulting 'kinetic rate 60 61 laws' have been implemented into reactive transport codes for several decades, an increasing 62 number of studies has consistently challenged this conceptual framework:

First, it has been theoretically and experimentally demonstrated that mineral reactivity is highly heterogeneous, resulting from the distribution of reactive sites at the fluid-solid interface¹⁴. The 'rate spectra' concept¹⁵, which provides a measurement of the rate distribution at the mineral surface in the spatial domain, was developed to indirectly capture this energetic landscape. 68 Second, the advent of nanoscale imaging of surface topography has resulted in the demonstration that crystal dissolution is a highly anisotropic process^{8, 16-24}. These studies 69 showed that the anisotropic reactivity of minerals results from the anisotropic distribution of 70 71 atomic positions in the crystal lattice, and may be described in the framework of the periodic bond chain (PBC) theory²⁵. This theory suggests that crystal faces may be sorted following 72 73 the number of chains of energetically strong bonds (PBCs) they contain, with the faces 74 containing the largest numbers of PBCs dissolving slower, and vice versa. Pollet-Villard et 75 al.²¹ further proposed that the recognition of the anisotropy of crystal reactivity challenged the 76 idea of a unique relation between the overall dissolution rate of a crystal and the Gibbs free 77 energy of reaction (ΔG), which is constitutive of the TST formulation, while questioning the 78 existence of a unique intrinsic dissolution rate constant for crystals.

Finally, silicate dissolution is accompanied with gradual physicochemical and structural modifications of their surface, resulting in the formation of nm- to μ m-thick silica-rich surface layers²⁶⁻³¹. Accounting for the transport properties of such layers, especially when developed under mildly aggressive conditions (circum-neutral pH, low temperature), was also proposed to be essential to develop reliable models of silicate dissolution^{23, 32}.

In a nutshell, all these studies converge towards the same conclusion: providing a better theoretical description of mineral dissolution crucially requires gaining knowledge on the relation between the atomic configuration of (and therefore, the energetic distribution at) the dissolving mineral surface and the overall dissolution rate of a given crystal.

Driven by this assertion, studies dedicated to the molecular-scale description of the silicate dissolution process following *ab initio* quantum mechanical calculations emerged some 20 years ago³³⁻³⁸. Such studies shed light on essential theoretical information regarding the dissolution process such as suggesting reaction paths, determining transition state configurations (i.e., bond lengths and angles) and calculating activation energies of the

hydrolysis reactions in various pH domains. They also independently confirmed that the 93 94 dissolution process cannot be boiled down to the kinetics of a single surface reaction. Actually, the large number of possible configurations of dangling atoms at the silicate surface 95 96 over the course of the dissolution translates into as many possible different hydrolysis 97 reactions, justifying the need for specific numerical simulations of the dissolution process at a 98 scale exceeding clusters of a few atoms. This was precisely one of the motivations for the development of kinetic models using a Monte Carlo approach (often abbreviated as kMC)^{9, 22,} 99 ³⁹⁻⁴⁷, whose parametrization may strongly rely on the results of *ab initio* calculations 100 mentioned above. However, with the noticeable exception of a few recent studies^{9, 22, 45}, to 101 102 date, most of these modelling studies were conducted with simple Kossel crystals⁴⁸, making 103 difficult the direct comparison of the outputs of the simulations with experimental data.

104 In the present study, we combined experimental measurements of the anisotropy of 105 silicate dissolution (face-specific topographic features and dissolution rates) with stochastic 106 simulations to critically assess the validity of a simple dissolution model. Because of its very 107 anisotropic crystallographic structure made of chains of silica tetrahedrons running parallel to 108 one of the main crystallographic axes, pyroxene was chosen as a case study. It was previously 109 shown that the anisotropic structure of this family of silicates (also known as inosilicates) resulted in a strong anisotropy of dissolution^{18, 23, 49}, intensifying the differences of reactivity 110 111 between the various faces that define their usual crystal habit. Owing to its simple chemical 112 composition (MgSiO₃) and structure (orthorhombic), enstatite was chosen as a model within 113 the pyroxene group.

After a brief description of the methods used and the ensuing information, we will discuss the experimental results (i.e., the anisotropy of enstatite dissolution rates and surface features observed using electron microscopy) in regard of pre-existing studies based on pyroxene dissolution. These results will then be compared to the outputs of the simulations, 118 which will lead to a validation of the dissolution model and a discussion of the wider 119 implications and conclusions for pyroxene dissolution and dissolution mechanisms at the 120 fluid-silicate interface.

121

122 **2. Materials and methods**

123 **2.1 Starting materials and preparation**

124 The enstatite samples used in this study come from Kilosa (Tanzania), and were supplied by Mawingu Gems Company. Negligible amounts of clinoenstatite (around a few wt. %) were 125 126 detected using X-ray diffraction (Fig. S1). Monolithic enstatite samples (up to several tens of 127 mm on a side) were cut with a diamond blade saw and polished down to the nanometer scale 128 through a multi-step abrasive sequence. The crystallographic orientation of each sample was 129 determined using an electron backscatter diffraction (EBSD) detector attached to a scanning 130 electron microscope (SEM) (TESCAN® Vega 2). The initial roughness of each surface was 131 measured at different scales with vertical scanning interferometer (VSI; ZYGO® NewView 132 7300). For each sample, the initial average arithmetic roughness (Ra), defined as the 133 arithmetic average of the absolute values of the roughness profile, ranged between 5 nm and 134 15 nm, and Rq (the roughness calculated with the root-mean-square of the vertical distance 135 between the surface elevation and the mean surface line) ranged between 19 nm and 70 nm. These initial roughness parameters were measured on $270 \times 360 \ \mu\text{m}^2$ images obtained using 136 VSI. 137

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2.2 Dissolution experiments and analytical procedures

Oriented samples were mounted in a passivated titanium support as designed by Daval et al.¹⁸, where a Viton® disk held with a screw creates a non-wetted reference area. Partially masked samples were dissolved in a synthetic acidic solution in 120 ml-PFA reactors at 90 °C for durations ranging from 6 hours to 3 weeks to check for the linearity of the surface retreatas a function of time.

144 The aqueous solutions were made with ultrapure deionized water (18.2 M Ω .cm) and 145 analytical grade nitric acid. The pH was adjusted to 0.0 ± 0.2 . Nitric acid was chosen to avoid 146 the dissolution of the titanium support that was observed in preliminary tests conducted with hydrochloric acid under similar conditions. Solution sampling was regularly carried out for 147 the analyses of Si, Mg and Fe using ICP-AES (Thermo ICAP 6000). The CHESS code⁵⁰ was 148 149 used to determine the *in situ* pH and saturation indices with respect to enstatite and secondary 150 phases. It was verified that all solutions were undersaturated with respect to any secondary 151 phase.

152 For each orientation, at least two solid samples were analyzed for topography 153 measurements. While the first one was periodically recovered to perform the analyses and put 154 back in reactor, the second sample was left in the reactor all over the duration of the 155 experiment. This protocol was followed to make sure that the reactivity of samples that 156 experience wetting/drying cycles to get time-resolved topography measurements remains 157 similar to the reactivity of samples continuously immersed in solution. The topography 158 measurements were performed using VSI in stitching mode (magnification: ×5) to estimate 159 the average changes in height between the unreacted reference surface and the reacted mineral 160 surface. For each oriented sample, dissolution rates were calculated according to the following equation (see e.g. Lüttge et al.⁵¹): 161

$$r_{exp}^{(hkl)} = \frac{\Delta h}{\Delta t} \bar{V}^{-1} \tag{1}$$

162 where $r_{exp}^{(hkl)}$ (mol.m⁻².s⁻¹) is the dissolution rate of the (*hkl*) face, Δh is the surface retreat (m), 163 Δt is the alteration duration (s) and \overline{V} (m³.mol⁻¹) is the molar volume of enstatite. As detailed 164 below, the minute lateral extension of etch pits (~ a few tens of nm) prevented the 165 investigation of individual pits by VSI even at high magnification (×100; lateral resolution ~ 300 nm), rendering impossible more sophisticated treatment of the surface topography usinge.g. rate spectra.

168 After completion of the surface topography measurements, the formation of nm-thick, 169 amorphous Si-rich layers (ASSL) was verified to make sure that the layer thickness was 170 negligible compared to the corresponding surface retreat measured by VSI. The samples were 171 either platinum- or carbon-coated and thin sections perpendicular to the investigated faces 172 were prepared by focused ion beam (FIB) milling using the FEI Helios 600 Nanolab dual-173 beam operating at CP2M (Marseille, France). The FIB Ga ion milling was carried out at an 174 ion beam voltage of 30 kV and with beam currents from 3 nA to 10 pA for the final steps. 175 Micrometer-thick sections were lifted out in situ using an Omniprobe 200 micromanipulator 176 and transferred to a half copper grid for final ion milling to electron transparency (final 177 thickness of about 100 nm). High-resolution transmission electron microscopy (HRTEM) and 178 scanning transmission electron microscopy (STEM) observations were performed on FIB 179 foils using a JEOL 2100F microscope operating at 200 kV, equipped with a field emission 180 gun. Energy dispersive X-ray (EDX) spectra were acquired in STEM mode to probe the 181 chemical compositions, with a focused electron beam (1 nm). When the FIB thin section 182 intersected etch pits (i.e., for the (100) and (010) samples), TEM was further used to 183 characterize their morphologies.

184

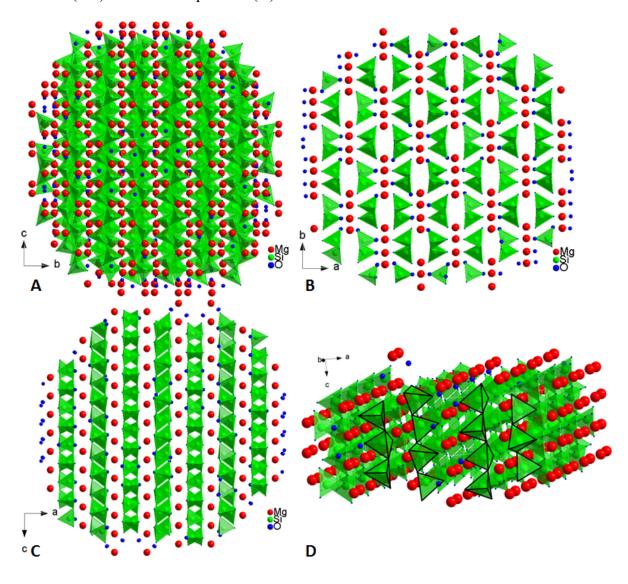
2.3 Modeling strategy

The stochastic approach for mineral dissolution studies has emerged in the mid-80's⁵². Since then, numerous studies have used stochastic simulations to describe mineral dissolution at the atomic scale, principally using simple Kossel crystals^{43, 47-48} (simple cubic crystal lattice; 6-fold coordinated atoms) but some have also applied them on more complex mineral⁹, 22, 41 and glass^{40, 44, 53} structures. These studies have shown the robustness of these models through their ability to reproduce etch pit shapes^{9, 22} and sometimes, by comparing modeled
and measured dissolution rates²².

These models are based on a simple relation that links the bond-breaking probability
to the activation energy of the hydrolysis of this bond⁵²:

$$P = e^{\frac{-\Delta E_a}{k_B T}} \tag{2}$$

where *P* is the bond-breaking probability, ΔE_a , the activation energy (J), k_B , the Boltzmann constant (J/K) and *T* the temperature (K).



196

Fig. 1. Projection of enstatite structure following [100] (A), [001] (B), [010] (C) zone axes and a rotation view of
the enstatite volume (D) to highlight the chains of silicate tetrahedrons. The Mg, Si and O atoms are represented
by red, green and blue spheres respectively. Si tetrahedrons are represented in light green.

201

2.3.1 Modeling enstatite crystal structure

Enstatite is an inosilicate made of chains of silicate tetrahedrons running parallel to the *c*axis. The crystal lattice of orthoenstatite (used in the present study) is orthorhombic and belongs to the Pbca space group. Hugh-Jones et al.⁵⁴ have provided the coordinates of the atomic positions (Table 1) that allow forming the enstatite cell with the following relations corresponding to the Pbca system:

X	У	Z	
¹ / ₂ - X	$\frac{1}{2} + y$	Ζ	
Х	¹⁄₂ - y	$^{1/2} + Z$	
$1/_{2} + x$	У	¹ / ₂ - Z	(3)
- X	-у	-Z	(3)
$1/_{2} + x$	½ - y	-Z	
-X	1⁄2 +y	¹ / ₂ -Z	
¹ / ₂ -X	-у	$\frac{1}{2} + Z$	

207 The lengths of the *a*, *b* and *c* axes are 18.233, 8.8191 and 5.1802 Å respectively and the 208 angles α , β and γ are equal to 90° (orthorhombic system).

The enstatite unit cell was created based on these parameters, and is composed of 16 atoms of magnesium, 16 atoms of silicon and 48 atoms of oxygen. The cell is then repeated following the three space dimensions in order to get a simulated crystal of several tenths to hundreds of nanometers on a side.

Mg and Si atoms were connected to O atoms according to the following rules: (i) Mg atoms are located in octahedral sites and Si atoms in tetrahedral sites (i.e., Mg atoms are connected to 6 O atoms and Si atoms are connected to 4 O atoms) and (ii) the closest O atoms were considered to create the coordination spheres surrounding each cation. The resulting modeled surfaces ((100), (010) and (001)) are shown in Fig. 1.

218

Atoms	x/a	y/b	z/c
Mg 1	0.3763	0.6541	0.8663
Mg 2	0.3769	0.4872	0.3589
Si 1	0.2715	0.3418	0.0506
Si 2	0.4736	0.3374	0.7981
O 1	0.1835	0.3407	0.0340
O 2	0.3114	0.5029	0.0430
O 3	0.3025	0.2224	0.8320
O 4	0.5622	0.3414	0.7980
O 5	0.4324	0.4836	0.6900
O 6	0.4483	0.1951	0.6030

219

Table 1. Atomic coordinates in enstatite cell⁵⁴ used in Eq. (3) to form the entire cell.

222 **2.3.2 Bond-breaking probabilities**

Most stochastic simulations performed at the atomic scale on silicate materials consider the cleavage of M-O-M bonds instead of single M-O bonds⁹. Hence, the oxygen atoms are only considered as bridges between two cations (O_{br}), and the cations connected to the oxygens of a specific Si or Mg atoms are referred to as their first coordination spheres⁹. In enstatite, three types of bonds exist: Mg-O_{br}-Mg, Mg-O_{br}-Si and Si-O_{br}-Si bonds.

228 Two different strategies may be considered to develop stochastic models: the former 229 considers that the release of a cation results from the sequential cleavage of each bond which 230 connects it to the surface, and the latter considers that the cation release results from the 231 simultaneous cleavage of all these bonds at a given iteration step. The difference between the 232 two methods stands in the number of information required to run a simulation (for a single 233 enstatite cell, 160 bonds need to be considered following the first strategy whereas only 32 234 atoms (16 Mg and 16 Si atoms; O atoms being considered as "bridges") are required for the 235 second strategy). For this reason, the second strategy is generally used and has previously proven successful^{9, 22, 41, 44, 53}. Accordingly, our simulations were run using the following 236 237 probability for the release of Mg and Si atoms:

$$P_M = e^{\frac{-n\Delta E_{M-O-Mg}}{k_B T}} e^{\frac{-m\Delta E_{M-O-Si}}{k_B T}}$$
(4)

238 where M = Mg or Si and *n* and *m* correspond to the number of Mg and Si atoms linked to the 239 considered M atom, respectively. This equation, together with knowledge of the connectivity 240 of each atom, represents the core description of the physical basis adopted for our stochastic 241 simulations. Importantly, more sophisticated relations may be found in the literature, which attempt to account for various physical processes such as lattice resistance^{34, 45}, steric 242 constraints⁹ or backward attachment reactions possibly resulting in self-healing of disrupted 243 Si-O_{br}-Si bonds^{34, 40-41, 44}. Importantly, even if the resulting stochastic models are physically 244 245 more robust, they also introduce significant degrees of freedom in the parametrization of the 246 resulting bond-breaking probabilities (see bond-breaking probability expressions and parametrization derived in, e.g., 9, 40). In contrast, the present work was intended to assess the 247 248 extent to which a stochastic approach with the simplest physical basis can satisfactorily 249 account for the main face-specific features of enstatite dissolution, explaining why we used 250 the simple relations provided by Eq. (4).

Various algorithms may be used to run stochastic simulations. In the present study, we followed a strategy close to the "random select and test" approach previously described and used in e.g. ^{40, 43} (see section 2.3.4). As described in these studies, this approach consists in scaling to unity the most probable event, and scaling accordingly the probabilities of all other events. Equation (4) then simply becomes:

$$P_M = P_{M-O-Mg}^n \times P_{M-O-Si}^m \tag{5}$$

with $0 < P_{M-O-Mg}$, $P_{M-O-Si} < 1$. According to *ab initio* and experimental studies, the most probable event is the detachment of an Mg atom bonded to the surface via a single Mg-O-Mg bond. The corresponding probability was then set to 0.99 and can be associated, by identification, to the Mg-O-Mg activation energy term in Eq. (4). The two other elementary probabilities ($P_{Mg-O-Si}$ and $P_{Si-O-Si}$) were calculated in order to observe the theoretical difference of activation energies between the hydrolysis of Mg-O-Mg and that of Mg-O-Si or Si-O-Si, respectively. Considering the *ab initio* data from^{36, 38} for the activation energy of Si-O-Si ($\Delta E_{Si-O-Si} = 69 \text{ kJ/mol}$) and Mg-O-Si ($\Delta E_{Mg-O-Si} = 59 \text{ kJ/mol}$) hydrolyses and the experimental data from ⁵⁵ for Mg-O-Mg hydrolysis ($\Delta E_{Mg-O-Mg} = 60 \pm 12 \text{ kJ/mol}$), the range of difference in activation energy that was explored is [0; 10 kJ/mol] for the {Si-O-Si; Mg-O-Si} pair and [0; 4 kJ/mol] for the {Mg-O-Mg; Mg-O-Si} pair.

267

268 **2.3.3 Dislocations**

Etch pits are known to nucleate at dislocations outcropping at crystal surfaces⁵⁶. In 269 270 order to compare the observed and simulated morphology of etch pits on each face, screw 271 dislocations were introduced in the model. The main dislocations for enstatite follow the 272 [001], [010] and [100] axes⁵⁷. Therefore, screw dislocations are perpendicular to the different 273 studied orientations, except for the (210) face. In order to propagate the dislocation in the 274 volume, the distances between the first atom (located at the center of the reactive surface) and 275 its neighbors in the xOy plan are calculated. The shortest distance defines the atom that will 276 be the next one belonging to the dislocation line. The same process is repeated until reaching 277 the opposite face of the simulated crystal. For the (210) face, a rotation of the volume is made 278 before applying these steps in order to respect the dislocation directions ([100] and [010]). 279 Finally, when all the atoms that belong to the dislocation line are identified, their bondbreaking probabilities are set to $1^{9, 22}$. 280

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- 282

2.3.4 Dissolution algorithm

The "random select and test" (RST^{40, 43}) and "divide and conquer" approaches (DaC^{43, 58}) are two different algorithms commonly used in stochastic simulations. Nowadays, the DaC algorithm is usually preferred because it requires less computer time. Furthermore, it provides a correspondence between iteration and time⁹. However, DaC algorithms cannot reproduce

simultaneous events, and favor a "layer-by-layer" removal of atoms⁴¹. For these reasons, we preferred using an approach close to the "primitive" RST despite its poor computation efficiency. Moreover, time cannot be associated *a priori* to a number of iterations. This relation has to be inferred using at least two experimental data sets (e.g., two dissolution rates for two different faces). By measuring mean dissolution rates for 4 different faces, we made sure that the problem was overconstrained, ensuring a well-established relationship between time and simulation steps (iterations).

294 The crystal is described by the coordinates of the Mg and Si atoms and the 295 connectivity of each atom to its neighbors follows the rules described in Section 2.3.1. Only 296 the cations that have an incomplete first coordination sphere (incomplete connectivity), are 297 considered to be located at the crystal surface, and may experience dissolution. For each Mg 298 and Si atom, an integer number indicates the three possible states of the atom: (i) dissolved, 299 (ii) at the crystal surface, or (iii) inside the crystal. This indicator allows counting the number 300 of dissolved cations and their nature (Mg or Si) and identifying the atoms located at the 301 surface in an efficient way.

302 The algorithm for simulating the dissolution process is as follows:

303 1. At each iteration step *k*, all cations of the simulated crystal volume are scanned
304 sequentially (Loop 1 in Fig. S2).

3052. For each surface cation, a random number Z uniformly distributed between 0306and 1 is generated. The probability of dissolution of that atom P_M is computed as307the product of the bond-breaking probabilities of the bonds that link it to the308crystal following Eq. (5). If $Z < P_M$, the atom is released (dissolved). If not, the309scan of the atoms is moving on (Loop 2 in Fig. S2).

310 3. When the scan of all atoms is completed, the first coordination spheres of the 311 remaining atoms are updated if necessary (i.e., when a removed atom was

15

312 belonging to the coordination spheres of one of the remaining atoms; cf. Loop 3 in 313 Fig. S2). Because the coordination spheres are modified, the probability of 314 dissolution P_M of the corresponding atoms are increased.

- 3154. The number of released Si and Mg atoms at iteration k is saved for post-316processing.
- 317

5. The iteration number is incremented and the process continues step 1.

318 **2.3.5 Model outputs**

The outputs of the simulations were used to document face-specific features of enstatite dissolution, such as (i) the mean dissolution rates at steady-state conditions, (ii) the thickness of the Si-rich surface layer that may result from preferential leaching of Mg (if any) and (iii) the etch pit morphology.

323 The dissolution rates may be calculated following two different approaches. First, the list of surface cations after a given iteration is used to calculate the corresponding mean 324 elevation of the surface $(z_{surface} = \sum_{i=1}^{N_{atome,surface}} z_i / N_{atom,surface})$ and infer the 325 corresponding mean surface retreat rate ([nm/iteration]), which can be converted into a 326 surface normalized dissolution rate $r_{mod,topo}^{(hkl)}$ ([mol/m²/iter]) using Eq. (1) (in which the 327 328 number of iterations is substituted for time). When steady-state conditions are reached (i.e., when $r_{mod,topo}^{(hkl)}$ becomes constant), this approach can be related to the dissolution rates 329 330 estimated using VSI (see section 2.2). Of note, the difference in terms of surface areas 331 between the simulated (0.33 µm² for the largest) and measured (dozens of mm²) surfaces preclude any direct use of the rate spectra concept¹⁵, so that in the present study, only the 332 333 mean surface retreat rates were subsequently used as a criterion to assess the correspondence 334 between simulated and measured dissolution rates.

A second approach considers the amount of Mg and Si atoms released at each iteration, as could be determined experimentally using ICP-AES solution analyses. Distinct rates based on Mg ($r_{mod,Mg}^{(hkl)}$ ([mol/m²/iter])) and Si ($r_{mod,Si}^{(hkl)}$ ([mol/m²/iter])) release were calculated following:

$$r_{mod,Mg}^{(hkl)} = \frac{\sum_{i=1}^{it} N_{Mg,i} * V_{cell}}{it * N_{Mg,cell} * S * \bar{V}}$$
(6a)

$$r_{mod,Si}^{(hkl)} = \frac{\sum_{i=1}^{lt} N_{Si,i} * V_{cell}}{it * N_{Si,cell} * S * \bar{V}}$$
(6b)

where *it* represents the iteration step at which the calculation is performed, $N_{M,i}$, the number of Mg or Si atoms released after the *i*th iteration, $N_{M,cell}$, the number of Mg or Si atoms in the cell (16), V_{cell} the enstatite cell volume, \bar{V} the molar volume of enstatite and *S*, the geometric surface area of the reactive surface.

While this approach eventually yielded results very close to the previous method, it 343 344 further provided information regarding the stoichiometry of the dissolution by comparing the evolution of the departure of the Mg and Si atoms, and eventually, regarding the existence 345 346 and thickness of a Si-rich surface layer, which was previously documented for inosilicates weathered experimentally^{18, 23, 59-61}. Since the model does not consider the backward reaction 347 of Si attachment to the surface (see discussion in ^{41, 62}), it only indicates a lower bound for the 348 349 thickness of the layer resulting from cation depletion, ignoring possible Si re-deposition 350 following an interfacial dissolution-reprecipitation mechanism.

Finally, for simulations run with dislocations, the resulting etch pits and surface retreats were calculated using Surfer[©]. The coordinates of the atoms at the surface were stored and used as an input file for Surfer. The minimum curvature method was used to calculate the mean surface retreat at a given iteration.

355

2.3.6 Linking time to iteration

As mentioned above, simulation results are normalized to the number of iterations instead of elapsed time. However, in order to compare modeled and measured dissolution rates, it is necessary to link a single iteration to a physical time increment. The correspondence between time and iteration was determined following Eq. (7):

$$t = \langle \frac{r_{mod}^{(hkl)}}{r_{exp}^{(hkl)}} \rangle it$$
(7)

361

362 **3. Results**

363 3.1 Face-specific dissolution rates of enstatite revealed experimentally

Fig. 2A shows the temporal evolution of the mean surface retreat measured using VSI. Whereas the (hk0) faces were reacted for durations of up to three weeks, the rapid increase of the roughness of the (001) face prevented the measurements of surface topography for durations exceeding a couple of days. The main results are as follows:

(i) the dissolution rate is constant through time (at least from the first experimentalmeasurements) for all of the four faces, within experimental uncertainties;

(ii) the dissolution rates of the samples left in the reactor all over the duration of theexperiments are similar to those that were periodically retrieved from the reactors;

(iii) enstatite dissolution is an anisotropic process (i.e., the slopes of the linear regressions differ from one face to the other). The face-specific dissolution rates $(r_{exp}^{(hkl)})$ observe the following trend: $r_{exp}^{(001)} \gg r_{exp}^{(210)} > r_{exp}^{(010)} \ge r_{exp}^{(100)}$. The mean values of dissolution rates are 71.8 ± 13.9, 8.5 ± 1.5, 3.0 ± 1.0 and 2.6 ± 0.6 nmol/m²/s for the (001), (210), (010) and (100) faces, respectively (Fig. 2B).

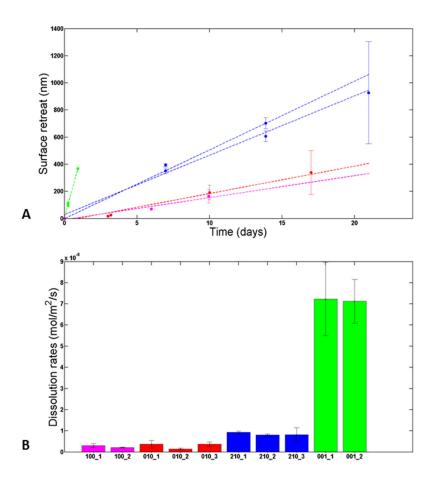




Fig. 2. A. Face-specific temporal evolution of the mean surface retreat measured with VSI and associated linear
regressions. B. Measured face-specific dissolution rates. For both graphs, magenta, red, green and blue colors
stand for the results obtained for (100), (010), (001) and (210) faces, respectively.

382 *3.2 Face-specific microstructural features revealed experimentally*

The etch pits possibly formed on each surface were too small to be properly investigated by VSI, whose resolution is close to 300 nm at the maximum 100xmagnification. Apart from the surface retreat between the masked and unmasked portions of the samples (Fig. 3), no specific topography feature could be evidenced using VSI.

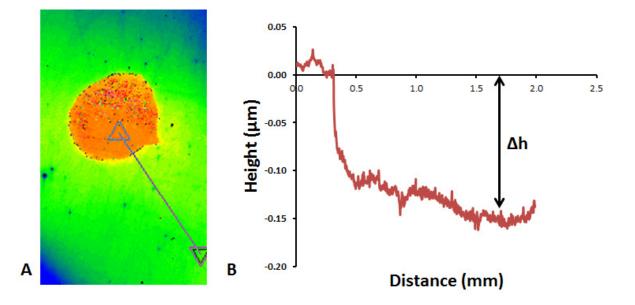


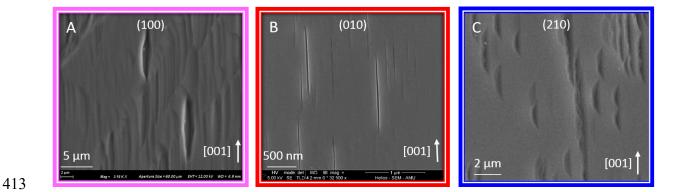


Fig. 3. A. Surface topography of the (001) surface dissolved for ~ 8h measured using VSI. The red spot represents the mask (non-reacted) area while the blue/green area represents the reacted surface. B. Topography of the surface (straight line in A) after dissolution. The upper part corresponds to mask area while the lower part corresponds to the reacted area.

393 SEM imaging of the reacted surfaces revealed that etch pits did nucleate on three of 394 the four investigated faces (Fig. 4), and confirmed that their lateral extension was too modest 395 to be imaged by VSI. The (100) and (010) faces exhibited similar lenticular pits elongated 396 following the *c*-axis (the major axis is more than 6 times larger than the minor axis). The 397 shape of the pits projected to the horizontal surface shows a central symmetry, consistent with the shape previously described in the literature for pyroxenes in general^{18, 60, 63-65}. Two types 398 399 of pits are visible on the (210) face: while the former is similar to the ones observed on the 400 (100) and (010) faces (with a small minor axis compare to the major axis), the latter, also 401 elongated following the c-axis, presents a wider minor axis (3 times smaller than the major 402 axis). In addition to this difference of minor-axis length, these pits differ from the ones 403 observed on the other faces by their non-symmetrical, half-moon shape. Whereas the lowest 404 points for the pits developed on the (100) and (010) faces are located at the center of the pits,

405 conversely, for pits developed on the (210) face, the lowest point is located at the center of the
406 major-axis but shifted on one edge of the minor-axis (Fig. 4C).

The dislocation density is also a function of crystallographic orientation. The number of dislocations has been calculated on each face by counting the number of etch pits observed by SEM on surface areas of $\sim 300 \ \mu m^2$. Of note, polishing scratches also represented an important source of etch pits. Because they can contribute to the global dissolution rate by exposing step sites, they have been taken into account in the calculation of the dislocation density.



414 Fig. 4. SEM images of the surface of (001) (A), (010) (B) and (210) faces reacted at pH 0 for 7 to 21 days. The 415 images reveal the nucleation of lenticular etch pits elongated following the [001] direction. Note the asymmetric 416 shape of the pits nucleated on the (210) face, as opposed to those developed on the other two faces.

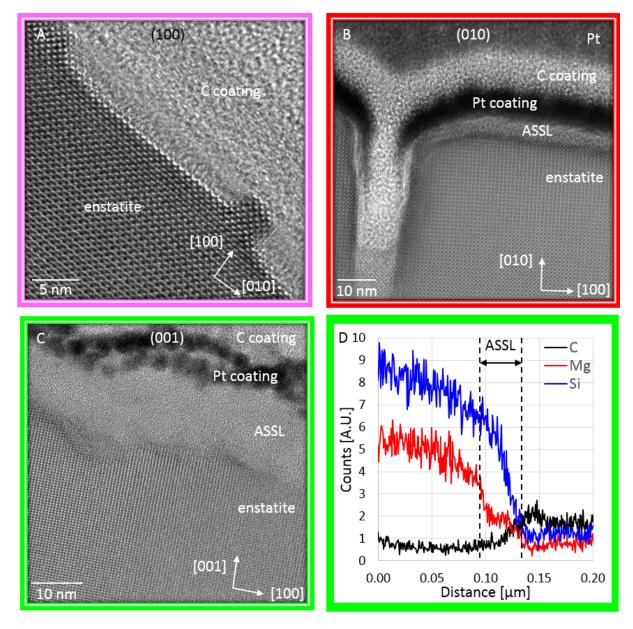
417

418 The dislocation density on the (100) and (210) faces was found to be similar (on the 419 order of $4.9 \pm 0.3 \times 10^8$ dislocations / cm²), and is about two orders of magnitude greater than that measured on the (010) face $(9.8 \times 10^6 \text{ dislocation / cm}^2)$. The dislocation density on the 420 421 (001) face could not be determined because of the rapid roughening of the surface, which 422 impeded the identification of individual etch pits. These dislocation densities are in agreement with other studies⁶⁶⁻⁶⁷, which reported dislocation densities ranging between 4.0 x 10^7 and 7.0 423 424 x 10^8 dislocations / cm². The close correspondence between the dislocation density calculated for the (100) and the (210) faces may be explained by the main orientation of screw 425

dislocations for the enstatite structure. As mentioned in section 2.3.3, the main dislocations in enstatite follow the [100], [010] and [001] directions⁵⁷. Therefore, outcropping dislocations at the (210) surface should represent the sum of the dislocation outcropping at the (100) and the (010) surfaces, which is consistent with our observations.

430 TEM investigations performed on FIB thin sections prepared on the reacted samples 431 revealed the occurrence of amorphous surface layers on (010), (210) and (001) samples, with 432 a thickness specific to the surface orientations (Fig. 5). The thickest layers were evidenced on 433 (001) samples (15-20 nm; cf. Figs. 5C-D). The layers developed on (210) and (010) samples 434 have similar thickness (≤ 4 nm; cf. Fig. 5B), whereas no surface layer could be clearly 435 evidenced on (100) samples (Fig. 5A). The layers developed on (001) samples were thick 436 enough to analyze their chemical composition with STEM-EDX, which revealed that they are 437 Si-rich and Mg-depleted (Fig. 5D). The similarity of these results with those reported by Daval et al.¹⁸ for diopside dissolved at pH 1 is noteworthy. Finally, it was possible to 438 439 determine the cross-section morphology of etch pits nucleated on the (100) and (010) faces, as 440 the FIB thin sections were realized in locations where etch pits were particularly abundant. 441 Regarding the (010) face, TEM images revealed that the pit geometry observes an axial 442 symmetry with respect to the [010] axis, and that the pit walls are particularly steep, forming an angle of $93^{\circ} \pm 2^{\circ}$ with the (010) surface (Fig. 5B). Similarly, the walls of the pits 443 444 developed on the (100) face formed an angle of $97^{\circ} \pm 5^{\circ}$ with the (100) surface, although the 445 pits appear to be flat-bottomed (Fig. 5A). Overall, these results confirmed that profilometry 446 techniques such as atomic force microscopy or vertical scanning interferometry would have 447 failed to reveal the 3D-geometry of such etch pits.

448

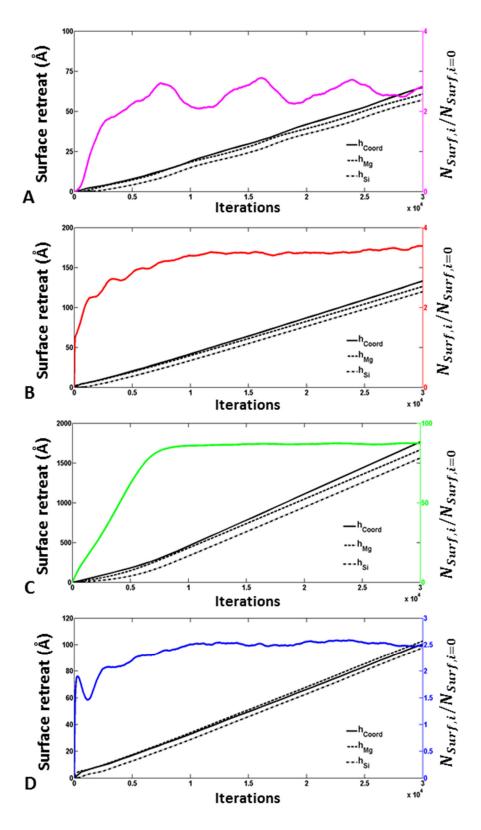


449

Fig. 5. TEM characterizations of FIB thin sections prepared on (100) (A), (010) (B), and (001) (C and D) reacted surfaces. HRTEM images in (B) and (C) reveal the formation of a nm-thick amorphous layer formed on the surface, with a sharp crystallographic boundary between enstatite and the surface layer. For the FIB thin section realized on (001) surface, STEM-EDX profiles measured parallel to the [001] direction reveal that the surface layer is Si-rich and Mg-depleted (D).

456 *3.3 Model outputs*

457 **3.3.1 Dissolution stoichiometry and steady-state dissolution rates**



458

459 Fig. 6. Outputs of the simulations conducted with the bond-breaking probabilities corresponding to the best 460 agreement between measured and modeled dissolution rates (see text for details) for (100) (A), (010) (B), (001) 461 (C) and (210) (D) faces. The evolution of the modeled surface retreat calculated following three different 462 methods (see text) is depicted with black lines. The color lines stand for the evolution of the number of surface

463 cations, normalized to the initial number of cations at the enstatite surface. Note that the increase of the number 464 of surface atoms is much greater for (001) face (about an 80-fold factor) than for the other (hk0) faces (between a 465 2.5- and 3.8-fold factor).

466

A common trait to all of the simulation outputs, irrespective to the set of bondbreaking probabilities that have been tested, is the attainment of a steady-state dissolution regime, which is characterized by a congruent release of Mg and Si cations and a constant dissolution rate (Fig. 6). This steady-state regime was found to result from the attainment of a constant number of atoms at the surface of each face, as illustrated in Fig. 6 (color lines).

472 During the initial transient period, Mg is released preferentially, and enstatite dissolution 473 rate based on Si release increases gradually. The duration and the shape of the transient period depend on the set of bond-breaking probabilities that are used to run the simulations and is a 474 475 function of surface orientation. In a general manner, the steady-state regime is achieved 476 earlier for the (hk0) faces than for the (001) face, for which the initial non-congruence of the 477 dissolution is also more pronounced (Fig. 6). As a consequence, thicker ASSLs are expected to build up on the (001) face, compared to the (hk0) faces. When one considers the set of 478 479 bond-breaking probabilities that allows for the best agreement between the modeled and 480 measured steady-state face-specific dissolution rates (see below), the modeled thickness of 481 ASSL is on the order of 1-2 atomic monolayers for all (*hk*0) faces, as opposed to ~ 10 nm for 482 the ASSL developed on the (001) face.

The modeled absolute values of steady-state dissolution rates and the relative differences between the reactivity of the four faces depend on the set of bond-breaking probabilities that were used to conduct the simulations. Considering a range of probabilities that is consistent with the literature (see section 2.3.2) and the dislocation density determined experimentally for each face, the modeled face-specific dissolution rates $r_{mod}^{(hkl)}$ observe the following trend: $r_{mod}^{(001)} \gg r_{mod}^{(hk0)}$. The relative differences between the modeled dissolution rates for the 489 various (hk0) faces depend on the set of probabilities used to run the simulations. The best 490 agreement between modeled and measured steady-state dissolution rates is obtained for P_{Mg-O-} $M_{g} = 0.99$; $P_{Mg-O-Si} = 0.4$ and $P_{Si-O-Si} = 0.0146$ (i.e., $\Delta E_{Si-O-Si} - \Delta E_{Si-O-Mg} = 10$ kJ/mol 491 and $\Delta E_{Mg-O-Mg} - \Delta E_{Si-O-Mg} = 2.7$ kJ/mol), for which the modeled face-specific 492 dissolution rates $r_{mod}^{(hkl)}$ observe the following trend: $r_{mod}^{(001)} \gg r_{mod}^{(010)} > r_{mod}^{(210)} > r_{mod}^{(100)}$. 493 494 Whereas the amplitude of the reactivity measured between the fastest and slowest dissolving 495 face is well reproduced by the model, one can note that it slightly overestimates the reactivity 496 of the (010) face (or slightly underestimates the reactivity of the (210) face).

497

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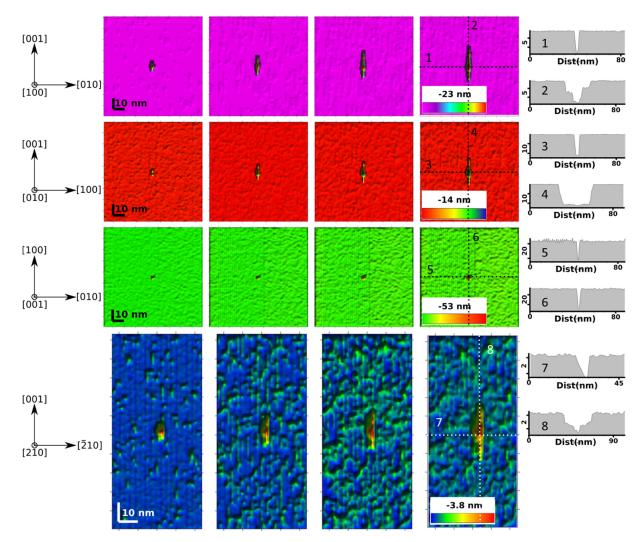
3.3.2 Morphology of modeled etch pits

499 The implementation of dislocation lines in the simulated crystals allowed to document 500 the morphology of etch pits for the four investigated faces. Fig.7 depicts the modeled surface 501 evolution of the four studied faces, centered on an outcropping dislocation line, for 502 simulations ranging from 0 to 2,000 iterations. Screw dislocation orientations were chosen following those determined by Skrotzki⁵⁷ for enstatite: [100] for (100) and (210) faces, [010] 503 504 for the (010) face and [001] for the (001) face. These results were obtained using the set of 505 bond-breaking probabilities corresponding to the best agreement between the modeled and 506 measured steady-state face-specific dissolution rates.

Etch pits growing on the (100) face were found to be lenticular and symmetric with respect to the *b*- and *c*-axes, respectively (cross-sections 1 and 2). Their aspect ratio evolves as a function of the reaction progress, as their length following the *c*-axis increases faster than along the *b*-axis. In addition, they exhibit a single lower point that may result from a slow step propagation (and thus, difficult pit opening), as suggested by the shape of their bottom along the *c*-axis. The bottom of the pits developed on the (100) face are surrounded by steep pit walls ($\theta \approx 93^\circ \pm 1^\circ$ between the surface and pit walls). The morphology of etch pits growing on the (010) face displays similar features (elongated following the *c*-axis, and symmetric with respect to the *a*- and *c*-axes, with similar length and width (\approx 5-10 nm) after 2,000 iterations), although the pits are deeper (\approx 20 nm against \approx 10-15 nm after 2,000 iterations) and thinner than those developed on the (100) face. Of note, their growth rate is lower than that of pits developed on the (100) face. The bottom of the pits developed on the (010) face is surrounded by steep pit walls ($\theta \approx 95^\circ$ between the surface and pit walls).

521 The morphology of etch pits growing on the (210) face is similar to that of etch pits 522 developed on (100) and (010) faces. However, their lenticular shape is not as well defined and 523 approaches that of a half-moon: indeed, one edge of the pit subparallel to the c-axis is 524 straighter than the other, which is more curvilinear. In addition, whereas the deepest point of 525 pits modeled on (100) and (010) faces is located at the center of the pit, the pits developed on 526 the (210) face are asymmetric (see cross- section 7) and the deepest point (3-4 nm) is located 527 at the center of the pit following the *c*-axis, but shifted on one edge of the minor-axis ([-210]). 528 Finally, although no etch pit could be evidenced experimentally on (001) faces, the 529 model predicts that small (≈ 10 nm) and deep (> 40 nm) subcircular etch pits may grow on the 530 (001) face if screw dislocations parallel to the c-axis are implemented. However, unlike the

531 other faces, etch pits developed on the (001) face reach a stable radius or tend to vanish, as a 532 result of the increasing roughness of the surrounding surface, possibly explaining why such 533 etch pits remained out of reach of our analytical characterizations.



534

Fig. 7. Evolution of modeled etch pits and associated cross-sections following the directions depicted by the
doted lines. For all pictures, magenta, red, green and blue colors stand for the results obtained for (100), (010),
(001) and (210) faces.

539 **4. Discussion**

540 4.1 Factors influencing the face-specific dissolution rates of enstatite and comparison

541 *with previous studies*

542 As reported above, the face-specific dissolution rates of enstatite range between 2.6 543 and 71.8 nmol/m²/s at pH 0 and T = 90 °C. These values are between one and two orders of 544 magnitude lower than expected using the dissolution rate law derived from powder

dissolution experiments conducted by Oelkers⁶⁸ (between 730 and 973 nmol/m²/s), which 545 represents the largest enstatite dissolution kinetics dataset that we are aware of. Such 546 547 discrepancies may either be ascribed to the contribution of edges and corners, whose reactivity is much greater than that of faces^{13, 46} and which are overrepresented when using 548 549 powders. It may also be due to the very low pH investigated in the present study, which may result in a saturation of proton surface sites⁶⁹, possibly leading to a weaker pH-dependence of 550 silicate dissolution rate than expected in the extreme acidic pH domain. In any case, the 551 552 present study illustrates the unsuitability of isotropic dissolution rate laws derived from 553 powder dissolution experiments to predict the amplitude and absolute values of face-specific dissolution rates, as pointed out in previous studies^{15, 21, 70}. 554

555 The results show that the dissolution rate of the (001) face is about one order of 556 magnitude greater than that of the other investigated (hk0) faces. Among these latter faces, the 557 dissolution rates of the (100) and (010) faces are similar within uncertainties, and are about 558 three times slower than that of the (210) face. If one considers the crystallographic similarities 559 existing between the (110) face of diopside and the (210) face of enstatite (both faces 560 correspond to the cleavage plane of these minerals, and intersect the highest density of Mg-O-561 Si bonds), these results are in excellent agreement with those obtained on diopside $(Ca_{0.5}Mg_{0.5}SiO_3)^{18}$, which also belongs to the pyroxene group (Fig. 8B). Note however that 562 563 the anisotropic reactivity of enstatite seems to be less pronounced than that of diopside. This 564 is likely due to the presence of Ca ions in the diopside structure, which offers more 565 combinations for the bond-breaking probabilities (and therefore, detachment rates) of Mg and 566 Si atoms. Indeed, the hydrolysis rates of Ca-O-Si and Ca-O-Ca bonds are faster than that of Mg-O-Si and Mg-O-Mg bonds, as demonstrated experimentally⁷¹ and indirectly confirmed 567 568 theoretically following *ab initio* calculations³⁸.

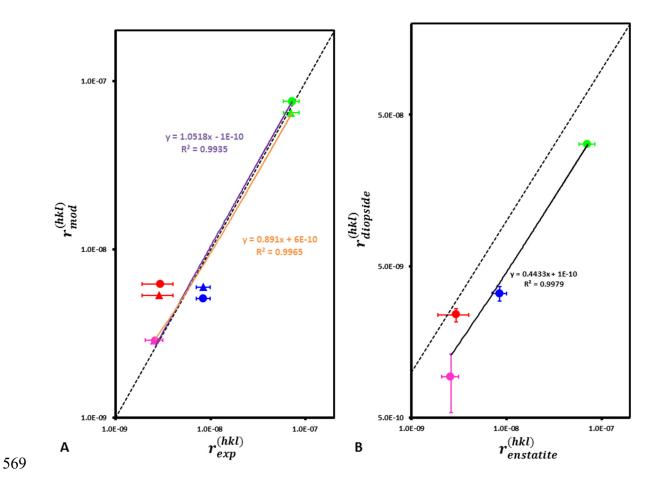


Fig. 8. A. Best agreement between modeled and measured face-specific enstatite dissolution rates. The triangles and circles stand for simulations conducted with and without dislocations, respectively. Note that the modeled dissolution rate of the (001) face is also affected because the time for one iteration changes as a function of the mean ratio between experimental and modeled dissolution rates (Eq. 7). B. Comparison between enstatite and diopside ¹⁸ face-specific dissolution rates. For both graphs, magenta, red, green and blue colors stand for the results obtained for (100), (010), (001) and (210) faces, respectively.

577 The factors that are most frequently invoked to account for the anisotropy of silicate 578 dissolution include (i) the crystallographic bonding structure and in particular, the 579 connectedness of silicate tetrahedrons^{18, 23, 72} (ii) the dislocation density and orientation^{18, 21, 23, 580 ⁷³⁻⁷⁴ and (iii) the formation of ASSLs, whose transport properties may differ as a function of 581 the crystallographic orientation^{18, 20, 23}.} 582 Considering the conditions that are thought be required for the development of 583 passivating ASSLs (i.e., oxic conditions and mildly acidic pHs, see ^{20, 23, 75-76}), the latter factor 584 (iii) can be safely ruled out in the present study.

585 Unravelling the relative contributions of factors (i) and (ii) to the observed anisotropic 586 reactivity may benefit from the comparison between the outputs of the simulations and the 587 experimental results. When the simulations are run without implementing any dislocation in 588 the enstatite structure, the reactivity of the (001) face is strikingly greater than that of the other 589 (hk0) faces, as observed experimentally (Fig. 6). Therefore, this suggests that the 590 connectedness of silicate tetrahedrons dictates the anisotropic reactivity of enstatite at first 591 order: as previously pointed out by Daval et al.¹⁸, the release of Si atoms from the (001) face 592 to the solution requires the cleavage of one Si-O-Si bond only, while it would require the (less 593 likely) simultaneous cleavage of two Si-O-Si bonds on the (hk0) faces, which are parallel to 594 the silicate tetrahedron chains.

595 The connectedness of SiO₄ tetrahedrons cannot be invoked to distinguish between the 596 reactivity of the three other investigated (hk0) faces, because it is the same for all of them. 597 However, because the outputs of the simulations show that the dissolution rates of these three 598 faces are different even without implementing any dislocation, this suggests that the 599 crystallographic bonding structure also exerts a strong control on the face-specific reactivity. 600 As it can be seen in Fig. 1, the Mg and Si atoms are organized following planes that are 601 parallel to the (100) face. If one supposes that the detachment rate of Si atoms connected to 602 two other Si atoms is lower than that of Mg atoms (in agreement with the respective 603 activation energies for the hydrolysis of Si-O-Si, Si-O-Mg and Mg-O-Mg bonds, see section 604 2.3.1), it can be assumed that the progression of the dissolution in the [100] direction will be 605 hampered by the sluggishness of the dissolution of these Si-rich planes. Conversely, the 606 detachment of accessible Mg atoms located below the first atomic plane of the (010) face may 607 contribute to destroying the first coordination spheres of the topmost Si atoms, which 608 eventually increase their probability of detachment. In turn, this explanation would account 609 for the fact that the slowest dissolving face is (100), and the dissolution rates inferred from the 610 simulations therefore observe the following trend: $r_{mod}^{(100)} < r_{mod}^{(010)} << r_{mod}^{(001)}$, the 611 (210) face representing an intermediate configuration between the (100) and (010) faces.

Finally, these simple crystallographic considerations do not account for the observation that the dissolution rate of the (210) face is greater than that of the (010) face. Interestingly, running the simulations with the appropriate dislocation density measured experimentally allows to obtain a global trend for the face-specific reactivity of enstatite which matches exactly to that measured experimentally, with $r_{mod,exp}^{(100)} < r_{mod,exp}^{(210)} < r_{mod,exp}^{(210)}$ $<< r_{mod,exp}^{(001)}$ (see details in section 4.2). These results confirm the critical contribution of dislocations to mineral dissolution rates (e.g., ^{9, 21, 74, 77-78}).

To sum up, both the crystallographic bonding structure and the presence of crystal defects (and in particular, dislocations) contribute to the observed anisotropic reactivity of enstatite, in agreement with previous studies dedicated to the face-specific dissolution rates of minerals.

623

624 *4.2 Assessing the agreement between measured and simulated rate data*

A total of 45 sets of activation energies for the thermally activated probabilities of breaking Mg-O-Mg, Mg-O-Si and Si-O-Si bonds were tested to cover the possible range of hydrolysis described in section 2.3.2. Three different complementary metrics were used to evaluate quantitatively the agreement between simulation outputs and experimental results: classical metrics such as the relative root mean square error (*RRMS*) and the relative mean error (*RME*), and an additional original metrics (*SaI*) based on a linear combination of the slope and the intercept of the line of best fit, i.e., the line obtained through linear regression
between modeled dissolution rates vs. measured dissolution rates. These metrics are defined
by:

$$RRMS = \frac{1}{N_E} \sqrt{\sum_{n=1}^{N_E} \left(\frac{r_{mod}^{(hkl)_n} - r_{exp}^{(hkl)_n}}{r_{exp}^{(hkl)_n}} \right)^2}$$

$$RME = \frac{1}{N_E} \sum_{n=1}^{N_E} \frac{r_{mod}^{(hkl)_n} - r_{exp}^{(hkl)_n}}{r_{exp}^{(hkl)_n}}$$

$$SaI = abs(1-a) + abs\left(\frac{b}{< r_{exp}^{(hkl)} >} \right)$$
(8)

where $r_{exp}^{(hkl)}$ (resp. $r_{mod}^{(hkl)}$) is the dissolution rate for face (*hkl*) estimated experimentally (resp. by the model), N_E is the number of experimental values (4 in our case), *a* is the slope of the best fit line, *b* is the intercept of the best fit line and $< r_{exp}^{(hkl)} >$ the average of all experimental dissolution rates.

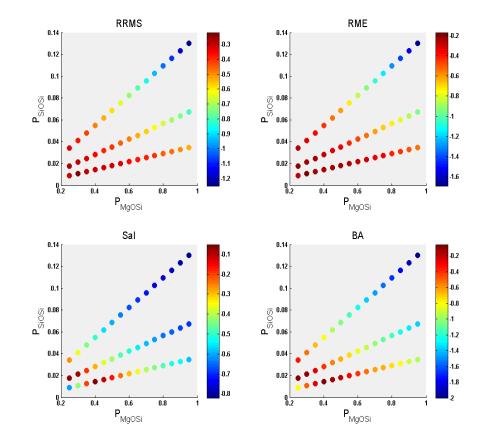
638 The RRMS index indicates how spread out are the differences between the modelled 639 values and the observed values or how close are, in average, these differences around the line 640 of best fit. The *RME* index allows detecting possible bias, i.e., if RME is significantly greater 641 than 0 (resp. lower than 0), the model overestimates (resp. underestimates) the observed 642 values. The information provided by the best fit line is gathered in the Sal index. Because of 643 differences in units (a is dimensionless, b has the dimension of the dissolution rate), the second term of SaI is divided by $\langle r_{exp}^{(hkl)} \rangle$. We used this reference for model performance 644 645 comparisons because it is a common reference for all data.

646 *RRMS-RME* indices and the *SaI* index provide different kinds of information. Any set 647 of probabilities (or their corresponding activation energies) that minimizes the *RRMS* and 648 *RME* indices does not necessarily minimizes the *SaI* index as well (e.g., the set of 649 probabilities that minimizes the *RRMS* and *RME* indices is $[P_{MgOMg} = 0.99, P_{SiOMg} = 0.3$ and 650 $P_{SiOSi} = 0.0109]$ (*RRMS* = 22% and *RME* = 17%), whereas it overestimates the dissolution rate 651 anisotropy (*SaI* = 0.52). On the other hand, the set that allows for the best *SaI* is $[P_{MgOMg} =$ 652 0.99, $P_{SiOMg} = 0.40$ and $P_{SiOSi} = 0.0146]$ (*SaI* = 0.06), corresponding to *RRMS* and *RME* of 653 30% and 22%, respectively). In order to compare the 45 sets of probabilities, we finally 654 defined a composite metric that we called best agreement (*BA*) for each set *i* by the following 655 formulation:

$$BA_{i} = \frac{1}{2} \left(\frac{RRMS_{i} - \min(RRMS)}{\max(RRMS) - \min(RRMS)} + \frac{RME_{i} - \min(RME)}{\max(RME) - \min(RME)} \right) + \frac{SaI_{i} - \min(SaI)}{\max(SaI) - \min(SaI)}$$
(9)

In this formulation, the three metrics are scaled by their max-min values, and we balanced the classical metrics *RRMS* and *RME* with the new metric *SaI*. Other formulations could have been used for *BA* but we privileged the balanced linear formulation that is more robust than other formulations based on single values like min-max values. Due to the small number of experimental data, more sophisticated composite metrics would have been questionable. Following this formulation, the smallest the *BA*, the better is the agreement between experimental dissolution rates and simulated dissolution rates.

Based on the *BA* metric, only a narrow range of probabilities provided a satisfactory agreement between simulation outputs and experimental data (Fig. 9) and one set of probabilities ([$P_{MgOMg} = 0.99$, $P_{SiOMg} = 0.4$; $P_{SiOSi} = 0.0146$]) yielded the lowest value of *BA* (BA = 0.05). This set has been selected to further discuss the outputs of the simulations below, although it is noteworthy that a couple of sets of probabilities also returns similarly low *BA* values (e.g., the two sets of probabilities [$P_{MgOMg} = 0.99$, $P_{SiOMg} = 0.25$; $P_{SiOSi} = 0.0177$] and [$P_{MgOMg} = 0.99$, $P_{SiOMg} = 0.3$; $P_{SiOSi} = 0.0212$] correspond to *BA* values of 0.07 and 0.09, 670 respectively), pointing towards the existence of a narrow range of possible P_{MgOSi} and P_{SiOSi}



671 (and therefore, of $\Delta E_{Si-O-Si} - \Delta E_{Si-O-Mg}$ and $\Delta E_{Mg-O-Mg} - \Delta E_{Si-O-Mg}$) values.

672

Fig. 9. Color maps of the agreement between modeled and measured dissolution rates in regards to the sets of
probabilities that have been tested. The browner the color, the better agreement. See section 4.2 for a description
of the *RRMS*, *RME*, *SaI* and *BA* indices.

676

677 The discrepancies between the results of the simulations conducted with and without 678 dislocations are shown in Fig. 8A. As mentioned above, the main impact of the 679 implementation of the right dislocation density for the (100), (010) and (210) faces consists in 680 an inversion between the reactivities of the (210) and (010) faces. Whereas the face-specific dissolution rates observe the following trend without dislocations : $r_{mod}^{(100)} < r_{mod}^{(210)} < r_{mod}^{(010)} <<$ 681 $r_{mod}^{(001)}$, it becomes $r_{mod}^{(100)} < r_{mod}^{(010)} < r_{mod}^{(210)} << r_{mod}^{(001)}$ when dislocations are added, in good 682 683 agreement with the experimental measurements. In detail, the implementation of dislocations 684 increased the dissolution rates of the (210) and (100) faces, while the reactivity of the (010) 685 face remains unaffected, probably because of the low dislocation density observed on this 686 face. Finally, the outcropping of dislocations at the surface of the (001) face has not been 687 considered, since it was not possible to evidence etch pits on the corresponding samples. Of 688 note, the implementation of dislocations also has an impact on the agreement between 689 simulation outputs and experimental results. Whereas the implementation of dislocations tend 690 to minimize the *RRMS* and *RME* values (*RRMS* = 22% and *RME* = 13% with dislocations vs. 691 RRMS = 30% and RME = 22% without dislocations), this also results in a modest increase of 692 the SaI (SaI = 0.11 vs. SaI = 0.05), implying that the dissolution rate anisotropy becomes 693 slightly underestimated. Overall, it can be concluded that adding dislocations to the model 694 slightly improves the general agreement between simulation outputs and experimental results 695 in terms of *RRMS* and *RME* but slightly degrades the account for the anisotropy of dissolution 696 rates (increase of the Sal value). However, the BA index remains unaffected (BA = 0.06 in 697 both cases), which indicates that for this set of probabilities, the simulations conducted with 698 dislocations are statistically equivalent to those run without dislocations.

To sum up, the model satisfactorily accounts for enstatite face-specific dissolution rates measured experimentally, using bond-breaking probabilities consistent with what can be inferred from literature. Moreover, adding dislocations to the simulations in proportions that are consistent with the analytical characterizations allows one to reproduce the order of the face-specific dissolution rates observed experimentally.

704

705

4.3 Comparison between observed and modeled etch pits and related implications for enstatite dissolution mechanisms

The improvement of the agreement between modeled and experimental dissolution rates is not the only interesting output resulting from the implementation of dislocations in the simulated crystals. It also offers the possibility to compare the morphology of simulated etch pits developed at the dislocation outcrop to their counterparts revealed by electron microscopy on the different faces of enstatite (Fig. 4). This represents an aspect of great interest, as it is
regularly searched for as a tracer of weathering conditions⁷⁸⁻⁸⁰.

712 Interestingly, both the lenticular shape, the orientation and the symmetry of the pits 713 generated numerically on (100) and (010) faces using the best set of probabilities (see 714 previous section) are consistent with those observed experimentally. The simulated and 715 experimentally observed pits are very elongated along the *c*-axis and their minor-axes follow 716 either the [010] (for pits developed on (100) faces) or the [100] (for pits developed on the 717 (010) faces) direction, respectively. These directions also represent symmetry axes for the 718 pits, resulting in the existence of a symmetry point at their center. The TEM characterizations 719 performed on the FIB thin section realized on the altered (010) and (100) faces further 720 indicate that the angle formed by the pit walls with the surface are in good agreement with the 721 outputs of the simulations.

722 A noticeable difference revealed by the model between the pits developed on the (100) 723 and (010) faces consists in the shape of their bottoms following the *c*-direction (Fig. 7). These 724 differences may be ascribed to the crystallographic structure of enstatite. Indeed, while the 725 deepening of pits formed on the (100) face requires to sequentially intersect Si-rich and Mg-726 rich planes, the deepening of pits formed on the (010) face entails that the dissolution takes 727 place in a single plane, resulting in a faster opening of the corresponding pits. This may 728 explain why modeled etch pits formed on the (010) face are flat-bottomed in the *c*-direction, 729 as opposed to the pits formed on the (100) face, since the propagation of the dissolution 730 following the *c*-axis will be easier in the case of the (010) face than the one of the (100) face. 731 Supporting this assertion, the sequential removal of Mg atoms from Mg-planes, which are 732 readily accessible for pits formed on (010) faces, will result in lowering the coordination of Si 733 atoms in the Si-planes, thereby accelerating the global propagation of the pit along the *c*-axis. 734 Such a mechanism is not possible for pits developed on the (100) face, where the widening of 735 a pit involves dissolving Mg- and Si-rich planes sequentially. Finally, it is noteworthy that 736 these differences in terms of pit morphology, which follow from the anisotropic structure of 737 enstatite, also result in a difference of reactivity of the pits themselves, with pits developed on 738 the (010) faces being more effective to enhance enstatite dissolution than those developed on 739 the (100) faces. Finally, TEM observations reveal that etch pits nucleated on the (100) face 740 are flat-bottomed following their minor axis ([010]), a feature that is not accurately 741 reproduced by the model. Possible explanations for this observation include the fact that etch 742 pits revealed experimentally may have investigated at a greater reaction progress than the 743 modeled ones, which result in a widening of the pit in the *b*-direction.

744 Regarding the modeled pits formed on the (001) face, their main features consist in 745 their narrow subcircular shape (5 nm) and important depth (> 20 nm). As reported above, the 746 simulations reveal that the diameter of the simulated pits never exceeds 5 nm because of the 747 gradual and global roughening of the surface, which may explain why no etch pits were 748 observed by VSI, SEM or TEM on the (001) samples altered experimentally. The absence of 749 a continued lateral growth of the pits in the (001) plane also suggests that dislocation etch pits 750 form on the (001) face (if any) have a negligible contribution to the dissolution rate of this 751 face.

752 The pits that have been simulated on the (210) face are different from the ones 753 simulated on the (100) and (010) faces. Their shape approaches that of a crescent, with one 754 straight edge along the *c*-axis on one side and a curvilinear edge on the other side. This shape 755 is consistent with that revealed experimentally for (210) samples (see Fig. 4), and very similar 756 to the one observed for pits developed on the (110) and (1 $\overline{1}0$) faces of diopside by Daval et 757 al.¹⁸. The topography profile of the pits following the c-axis is similar to the one observed on 758 the (100) face, with a deepest point ($\approx 2.0 - 2.5$ nm) located at the center of the pit. The main 759 difference between the pits simulated on this face and those simulated on the (100) and (010)

760 faces is revealed when considering the topography profile of the pit following the minor-axis, 761 which is strongly asymmetric. Whereas the angle between the (210) surface and the pit wall at 762 the straight edge is very steep ($\theta \approx 95^\circ$), the other one is much less sharp ($\theta \approx 113^\circ$). Although 763 it was not possible to get a FIB foil across a single etch pit nucleated on the (210) face, it is 764 worth mentioning that this asymmetry was also observed for pits developed on the (110) face 765 of diopside (see atomic force microscopy (AFM) measurements in ¹⁸). This asymmetry is due to the fact that the direction of the dislocation is not orthogonal to the (210) face. An 766 767 interesting consequence of this specific geometry is that the entire simulated pit is not visible 768 in Fig. 7, since part of the pit is located below the surface of the face. Such features may correspond to the so-called "etch tubes"⁷⁷ or "etch tunnels"⁸¹ sometimes reported in the 769 770 literature, which cannot be imaged using classical surface sensitive techniques such as VSI or 771 AFM.

772 Finally, the pit geometry revealed by the numerical simulations also has broader 773 consequences for the practical measurement of crystal dissolution rates. As can be seen in Fig. 774 6D, the dissolution rate of the (210) face based on Mg release exceeds that calculated using 775 the overall surface topography. Such a "hidden" contribution to crystal reactivity may help 776 explain why face-specific mineral dissolution rates determined from solution chemistry 777 measurements sometimes overestimate dissolution rates estimated using surface sensitive 778 techniques, such as VSI²⁴. Furthermore, considering that the dislocation network in crystals 779 can be connected to the surface as a result of pit opening, intra-crystalline dissolution may 780 occur. A detailed understanding of the solution chemistry within single pits then becomes crucial, since concentration gradients can affect the reactivity of the etch pit⁷⁸. 781

To sum up, the etch pits modeled on (100), (010) and (210) are very similar to the ones observed on enstatite samples. The orientation, shape, and symmetry of the pits are correctly predicted by the model, and result from the crystallographic structure of enstatiteand orientation of dislocation lines.

786

4.4 Relation between the dissolution regime and the formation of Si-rich surface layers

787 As shown in Fig. 6, the transient regime, which is characterized by a non-788 stoichiometric release of Mg and Si atoms and a variable dissolution rate, spans over 7,500 to 789 8,250 iterations (depending on the considered face) corresponding to 2.7 ± 1.0 to 2.9 ± 1.0 790 days, when the best set of probabilities is selected (section 2.3.6). This result suggests that the 791 dissolution rates estimated experimentally for the (100), (010) and (210) faces were actually 792 measured during the steady-state regime, where the dissolution is stoichiometric and the rate is constant, and may explain why the very first VSI measurements of surface retreats 793 794 conducted on the (100) and (010) faces fall slightly below the regression trend line. 795 Conversely, part of the measurements carried out on the (001) faces might have been 796 performed during the transient regime, although this assertion is not supported 797 experimentally, since the measured surface retreats observe a linear temporal trend. This 798 result is not totally surprising, considering the expected modest evolution of the dissolution 799 rate with time inferred from the numerical outputs of the simulation for this face (Fig. 6), 800 which would imply that any deviation from the linear trend would fall within experimental 801 uncertainties.

From a physical standpoint, the model outputs suggest that the transient regime corresponds to the period where the number of surface atoms increases. The number of atoms at the surface increases by a 2.5-, 2.8-, 3.5-, and 80 fold-factor for the (100), (210), (010) and (001) faces, respectively. After this transient regime, the number of each surface cation reaches a constant value, resulting in a steady-state dissolution rate. Prior to reaching the steady-state regime, the dissolution rates based on Mg or Si release have opposite trends: while the Mg release rate decreases, enstatite dissolution rate based on Si release increaseswith time.

The attainment of a steady-state regime thereby appears intimately connected to the dynamics of Si release, which can be explained by the large differences existing between the detachment rates of Mg and Si atoms: the preferential detachment of Mg atoms will result in a depletion of the first coordination sphere of Si atoms, in turn increasing their release rates. The simultaneous attainment of a constant dissolution rate and a constant number of Si surface atoms for the 4 faces further suggests that the mean coordination of Si surface atoms also reached a steady-state after the transient regime.

817 This divergence in the dynamics of Si and Mg release has another important 818 consequence: during the transient regime, the simulations predict that the preferential release 819 of Mg atoms results in the formation of an Mg-depleted / Si-rich surface layer. According to 820 the simulation outputs, the thickness of the leached layer is 3.8, 6.0, 6.9 and 107 Å for (100), 821 (210), (010), and (001) faces, respectively. Interestingly, the model therefore predicts that 822 thick surface layers should develop on the (001) face, whereas they should be much thinner 823 on (hk0) faces, which is consistent with the TEM results described in section 3.3, and the results reported by Daval et al.¹⁸ for diopside dissolution. However, the model systematically 824 825 underestimates the actual thickness of the layer, which may be ascribed to the fact that it 826 neither accounts for (i) the spontaneous reorganization of the Mg-depleted layer, such as the 827 condensation of silanol groups, which may be associated to a global variation of the volume of the surface layers, as suggested in previous studies (e.g. ⁸²⁻⁸³); nor for (ii) the backward 828 829 reactions of Si attachment to the surface layer, following the alternative interfacial dissolution-reprecipitation mechanism^{26, 60-61, 84}. Here, and as emphasized in previous kMC 830 studies⁶², the outputs of the model indirectly support that the preferential alkali / alkaline earth 831

depletion during silicate dissolution is limited to the topmost layers of the minerals, and that
ASSL formation should, *at least partly*, result from Si redeposition²³.

To sum up, the comparison between the experimental data and the simulation outputs suggests that the duration of the transient period is reasonably well reproduced by the model. In addition, the model predicts the formation of Mg-depleted / Si-rich layers, although their actual thickness remains underestimated. This latter result indirectly reveals that certain mechanisms that are not accounted for by the model (e.g. Si attachment reactions; condensation of silanol groups) actually occur over the course of enstatite dissolution.

840

841 5. Conclusions and perspectives

842 In this study, we focused on the agreement between the outputs of stochastic atomic-843 scale dissolution simulations and the results obtained on face-specific enstatite dissolution 844 experiments carried out at 90 °C and pH 0 (rate data and structural observations of the faces). 845 Nearly 200 simulations were conducted to demonstrate that the anisotropy of enstatite 846 dissolution rate can be satisfactorily reproduced using bond-breaking probability ratios (and 847 therefore, activation energy differences) that are consistent with the existing literature 848 regarding the hydrolysis of Mg-O-Mg, Mg-O-Si and Si-O-Si bonds. On the same footing, the 849 model also correctly predicts various face-specific features, such as the orientation, symmetry, 850 and shape of dislocation etch pits. From a physical chemistry standpoint, this agreement gives 851 rise to the following two perspectives with respect to silicate dissolution and the silicate-water 852 interface:

(i) Nowadays, *ab initio* calculations are generally used to feed kMC simulations (e.g. ⁹,
^{22, 45}). Conversely, our study suggests that kMC simulations have the ability to be a powerful
tool to constrain a range of activation energies for the hydrolysis of bonds that are not

856 available in the current literature, and/or to validate the values resulting from ab initio 857 calculations. For instance, the value of $\Delta E_{Mg-O-Mg}$ we used was selected from an experimental work⁵⁵, because to the best of our knowledge, no study provided a theoretical value for this 858 859 parameter. If the agreement between modeled and simulated rates and etch pit geometry is 860 taken for granted, it could be immediately transposed to the diopside structure, for which farfrom-equilibrium rate data already exist¹⁸, making possible the determination of a possible 861 862 range for parameters such as $\Delta E_{Mg-O-Ca}$, $\Delta E_{Ca-O-Ca}$ or $\Delta E_{Ca-O-Si}$ (note that *ab initio* data already 863 exist for this latter parameter, see 38). This will be the subject of an upcoming paper.

864 (ii) On the same footing, a similar approach could be usefully transposed to other
865 silicate structures for which rate data already exist (see ⁷¹, which report far-from-equilibrium
866 rate data for a series of eight endmember orthosilicate minerals (M₂SiO₄) which varied only
867 by the nature of the divalent cation M they contain).

Conversely, we showed that the model underestimates the thickness of ASSLs formed on the various faces of enstatite. In itself, this result already provides insights into the dynamics of the dissolution process, as previously pointed out by Zhang and Lüttge⁶²: thick (i.e., several 10s of nm) ASSLs cannot be formed by a pure leaching mechanism only. This indicates where future kMC efforts should be directed, as the formation, growth and maturation of such layers are regularly suggested to influence the reactivity of the underlying substrate, at least in SiO₂(aq) rich solutions and mildly acidic pHs^{20, 31, 75-76}.

875

876 Acknowledgements

We warmly thank G. Morvan and R. Boutin (LHyGeS, Strasbourg) for their help with EBSD
and ICP-AES measurements. M. Cabié (CP2M, Aix-Marseille) and T. Dintzer (ICPEES,
Strasbourg) are acknowledged for their help with the preparation of the FIB thin sections and

880 for providing high resolution SEM images of etch pits. A.B. thanks the University of

881 Strasbourg for funding his PhD grant.

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